## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:	
Won-Ick Jang, et al.	Art Group:
Application No.:	Examiner:
Filed:	
For: STICTION-FREE MICROSTRUCTURE RELEASING METHOD FOR FABRICATING MEMS DEVICE - UTILITY	

Assistant Commissioner for Patents Washington, D.C. 20231

## TRANSMITTAL OF FORMAL DRAWINGS

Sir:

Enclosed herewith for filing in the above-identified U.S. Patent Application are the formal drawings, 8 sheets including 12 Figures. Applicant hereby authorizes any additional extension or petition fees under 37 C.F.R. §1.17 or credit for any overpayment to our Deposit Account No. 02-2666. A copy of the Fee Transmittal sheet is enclosed.

Respectfully submitted,

BLAKELY, SOKOLOFF, TAYLOR & ZAFMAN

Dated: 12/28/00

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FIG. 1

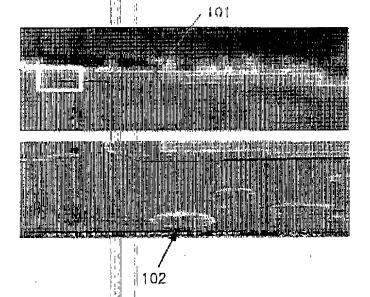
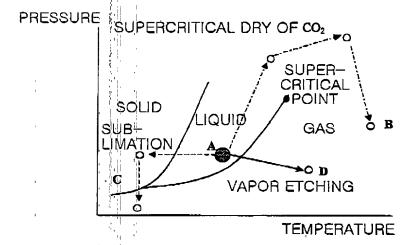


FIG. 2



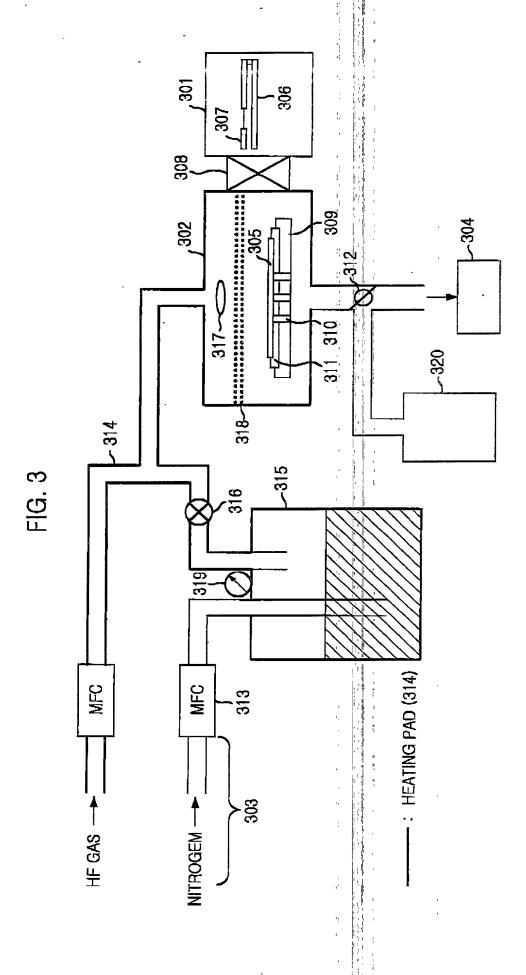


FIG. 4

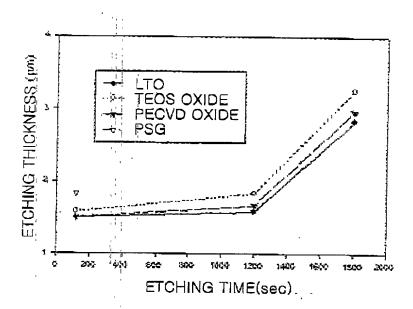


FIG. 5

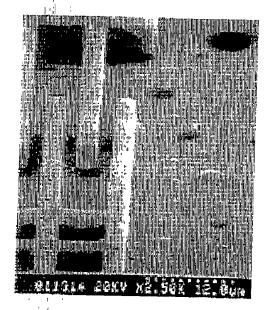


FIG. 6

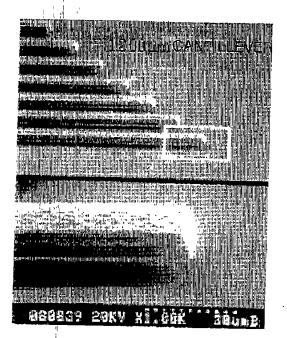


FIG. 7

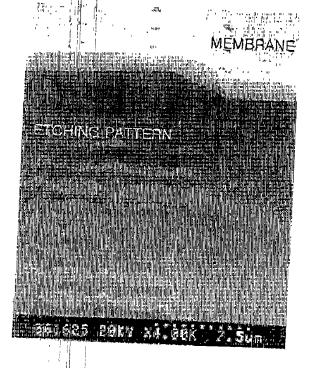


FIG. 8

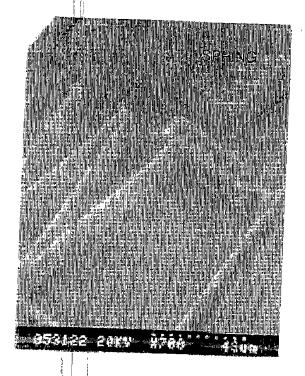


FIG. 9

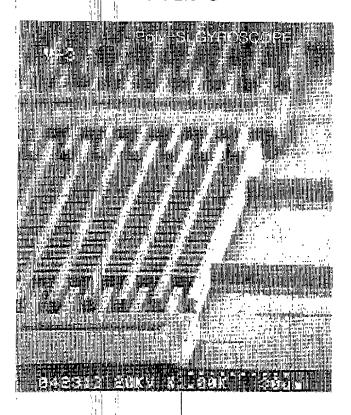


FIG. 10

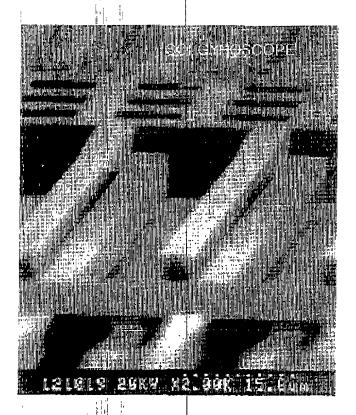


FIG. 11

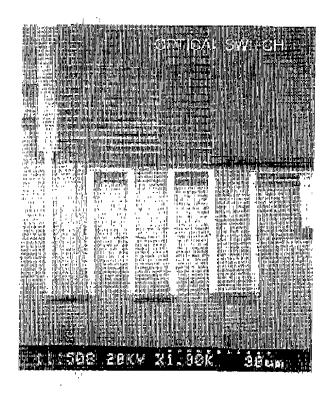


FIG. 12

